

10/576120

IAP15 Rec'd PCT/PTO 18 APR 2006

Docket No.: 071971-0569

PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of

Akio MISAKA

Application No.:

Group Art Unit:

Filed: April 18, 2006

Examiner:

For: PHOTOMASK AND PATTERN FORMATION METHOD AND MASK DATA
GENERATION METHOD USING THE SAME

PRELIMINARY AMENDMENT

Mail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

Prior to examination of the above-referenced application, please amend the application as follows:

Amendments to the Specification begin on page 2 of this paper.

Remarks / Arguments begin on page 3 of this paper.